AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended) A thin film phototransistor, comprising:
 - a gate electrode;
 - a gate insulation film provided on the gate electrode;
 - a photosensitive semiconductor film laminated on the gate insulation film;
 - a source electrode provided on the photosensitive semiconductor film; and
 - a drain electrode provided on the photosensitive semiconductor film,
- an end portion of the source electrode and an end portion of the drain electrode being separated with a predetermined distance,

the source electrode and/or the drain electrode including a superimposition area for being horizontally superimposed on the gate electrode, and the superimposition area including at least one portion having translucency, wherein photoexcitation carriers are generated in the gap formed between the source and drain electrodes and the superimposition areas of both the source and drain electrodes.

- 2. (Original) The thin film phototransistor as set forth in claim 1, wherein:
- the portion having translucency is formed by a transparent conductive film in the source electrode and/or in the drain electrode.
- 3. (Original) The thin film phototransistor as set forth in claim 2, wherein: the transparent conductive film is a transparent conductive oxide film.

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- 4. (Original) The thin film phototransistor as set forth in claim 1, wherein: the source electrode and/or the drain electrode is formed by a metal film, and the portion having translucency is formed by providing an opening section.
- 5. (Previously Presented) An active matrix substrate, comprising: electrical wirings in a form of a lattice pattern;
- a switching thin film transistor provided for each square of the lattice pattern and connected to the electric wirings; and
- a photo-sensor thin film transistor connected to the switching thin film transistor, the photo-sensor thin film transistor being made of the thin film phototransistor as set forth in claim 1.
- 6. (Previously Presented) An active matrix substrate, comprising: electrical wirings in a form of a lattice pattern; and
- a thin film transistor provided for each square of the lattice pattern and connected to the electric wirings, the thin film transistor having both a switching function and a photo-sensing function, the thin film transistor being made of the thin film phototransistor as set forth in claim 1.
- 7. (Previously Presented) The active matrix substrate as set forth in claim 5, wherein: a drain electrode of the thin film phototransistor is connected to a charge accumulation capacitor.

8. (Previously Presented) The active matrix substrate as set forth in claim 5, wherein:

the electric wirings in a form of a lattice pattern include a wiring connected to a source electrode of the thin film phototransistor, and the wiring is made of a transparent conductive film and formed on a same layer as that on which the source electrode is formed.

9. (Original) The active matrix substrate as set forth in claim 8, wherein:

the transparent conductive film is a transparent conductive oxide film.

10. (Previously Presented) The active matrix substrate as set forth in claim 5, wherein:

the electric wirings in a form of a lattice pattern include a wiring connected to a source electrode of the thin film phototransistor, and the wiring is made of a transparent conductive film and a metal film, and the transparent conductive film is formed on a same layer as that on which the source electrode is formed.

- 11. (Original) The thin film phototransistor as set forth in claim 10, wherein:
 - the transparent conductive film is a transparent conductive oxide film.
- 12. (Currently Amended) An image scanning device, comprising:

the active matrix substrate as set forth in claim 5, as <u>a</u> two dimensional image scanning

means element.

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13. (Currently Amended) The image scanning device as set forth in claim 12, further comprising:

light irradiating means devices for carrying out light irradiation with respect to the active matrix substrate, the light irradiating means devices being provided on a side opposite to a side for image scanning of the active matrix substrate.